, A			1.55	l m t
I. Number		Search Text	DB	Time stamp
1	1752	((118/719) or (414/939) or (156/345.31) or	USPAT;	2003/08/08 19:59
2	11	(156/345.32)).CCLS. (((118/719) or (414/939) or (156/345.31)	US-PGPUB USPAT;	2003/08/08 19:57
4	11	or (156/345.32)).CCLS.) and (ash\$3 with	USPAT; US-PGPUB	2003/00/00 19:3/
1		atmospher\$3 with pressure)	30 19100	
3	324	ash\$3 with atmospher\$3 with pressure	USPAT;	2003/08/08 19:57
		The state of the s	US-PGPUB	
4	139	ash\$3 with "atmospheric pressure"	USPAT;	2003/08/08 19:57
		• • • • •	US-PGPUB	
5	76	ash\$3 with "atmospheric pressure"	EPO; JPO;	2003/08/08 19:58
			DERWENT	
6	1	c23c016\$.ipc. and (ash\$3 with "atmospheric	EPO; JPO;	2003/08/08 19:59
7	4 4	pressure")	DERWENT	2002/00/00 10 50
'	11	(chamber with ash\$3 with "atmospheric pressure")	EPO; JPO; DERWENT	2003/08/08 19:59
8	23	pressure	EPO; JPO;	2003/08/08 20:00
	25	(additing atom demodphotic pressure /	DERWENT	
_	208	(118/\$.ccls. 156/345.\$.ccls.) and	USPAT;	2003/08/08 12:32
		((monitor\$3 determin\$3 measure\$3) with	US-PGPUB	
		(particle particulate debris) with		
		surface)		
-	2550	(118/\$.ccls. 156/345.\$.ccls.) and	USPAT;	2003/08/08 12:32
		((monitor\$3 determin\$3 measure\$3) with	US-PGPUB	
_	1 4 1 4	(thickness))	HCDAM -	2002/00/00 10 20
-	1414	(118/\$.ccls. 156/345.\$.ccls.) and ((monitor\$3 measure\$3) with (thickness))	USPAT; US-PGPUB	2003/08/08 12:32
_	113	((monitors) measuress) with (thickness)) (118/\$.ccls. 156/345.\$.ccls.) and	USPAT;	2003/08/08 13:09
	113	((monitor\$3 measure\$3) with (particle	US-PGPUB	2003/00/00 13:09
		particulate debris) with surface)	35 25255	
-	9	5837094.URPN.	USPAT	2003/08/08 12:45
-	999	(monitor\$3 measure\$3 detect\$3) with	USPAT;	2003/08/08 19:50
		(particle particulate debris) with surface	US-PGPUB	
		with (wafer substrate semiconductor)		
-	48978	c23c016\$.ipc.	EPO; JPO;	2003/08/08 13:36
_	0	(monitores mongueses detectés) with	DERWENT	2002/00/00 12 12
-	U	(monitor\$3 measure\$3 detect\$3) with (particle particulate debris) with surface	EPO; JPO; DERWENT	2003/08/08 13:11
		with (wafer substrate semiconductor)	DEKMENI	
-	0		USPAT;	2003/08/08 13:32
		(156/345.32)).CCLS.	US-PGPUB	=: : : : : : : : : : : : : : : : : : :
-	1752	((118/719) or (414/939) or (156/345.31) or	USPAT;	2003/08/08 19:50
		(156/345.32)).CCLS.	US-PGPUB	
-	105	(((118/719) or (414/939) or (156/345.31)	USPAT;	2003/08/08 13:36
		or (156/345.32)).CCLS.) and ((monitor\$3	US-PGPUB	
		<pre>detect\$3 measur\$4) with (particle particulate dust))</pre>		
_	48978	c23c016\$.ipc.	EPO; JPO;	2003/08/08 13:36
	10370		DERWENT	2003,00,00 13.36
-	59	4693777.URPN.	USPAT	2003/08/08 13:55
-	103	c23c016\$.ipc. and ((monitor\$3 detect\$3	EPO; JPO;	2003/08/08 15:51
		measur\$4) with (particle particulate	DERWENT	
	_	dust))		
-	2	09/945,454	USPAT;	2003/08/08 15:42
_	_	00/045454	US-PGPUB	0000 /00 /00 == ==
-	2	09/945454	USPAT;	2003/08/08 15:42
_	121	((transfer\$4 transport\$3) with chamber)	US-PGPUB EPO; JPO;	2003/08/08 15:54
	171	and ((monitor\$3 detect\$3 measur\$4) with	DERWENT	2003/00/00 13:34
		(particle particulate dust))	DUINTUN I	
-	2388	((transfer\$4 transport\$3) with chamber)	USPAT;	2003/08/08 15:54
		and ((monitor\$3 detect\$3 measur\$4) with	US-PGPUB	,,,
		(particle particulate dust))		
-	122	((transfer\$4 transport\$3) with chamber)	USPAT;	2003/08/08 15:54
		with ((monitor\$3 detect\$3 measur\$4) with	US-PGPUB	
		(particle particulate dust))		
-	57	((transfer\$4 transport\$3) with chamber)	EPO; JPO;	2003/08/08 15:55
		with ((monitor\$3 detect\$3 measur\$4) with	DERWENT	
_	76	<pre>(particle particulate dust)) ((transfer\$4 transport\$3) with chamber)</pre>	EDO. IDO.	2002/00/00 16:04
	, 0	same ((monitor\$3 detect\$3 measur\$4) with	EPO; JPO; DERWENT	2003/08/08 16:04
		-(particle-particulate-dust)	DERWEN1	

-	194	((transfer\$4 transport\$3) with chamber)	USPAT;	2003/08/08 16:28
20		same ((monitor\$3 detect\$3 measur\$4) with	US-PGPUB	
		(particle particulate dust))		:
-	2	118/719.ccls. and imahashi.in.	USPAT;	2003/08/08 17:01
			US-PGPUB	
-	1	("5909276").PN.	USPAT;	2003/08/08 20:03
			US-PGPUB	